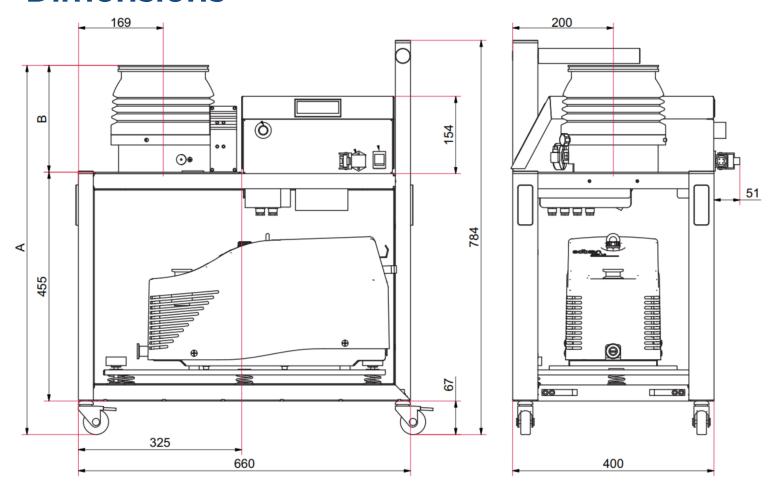
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Pfeiffer HiCube 80 Pro **Technical Specifications**

Pumping station	HiCube 80 Pro			
Flange (in)		DN 40 ISO-KF	DN 63 ISO-K	DN 63 CF-F
Pumping speed for Nitrogen N ₂	l/s	35	67	67
Ultimate pressure				
with Piston pump XtraDry 150	mbar	< 1 · 10-7	< 1 · 10-7	< 5 · 10 ⁻¹⁰
with Rotary vane pump PentaLine	mbar	< 1 · 10-7	< 1 · 10-7	< 5 · 10 ⁻¹⁰
Pumping speed backing pump at 50 Hz				
Piston pump XtraDry 150	m³/h	7.5	7.5	7.5
Rotary vane pump Penta 10	m³/h	11	11	11
Rotary vane pump Penta 20	m³/h	22	22	22
Rotary vane pump Penta 35	m³/h	34	34	34
Weight pumping station:1)				
with Piston pump XtraDry 150	kg	69.2	69.2	70.6
with Rotary vane pump Penta 10	kg	81.2	81.2	82.6
with Rotary vane pump Penta 20	kg	82.2	82.2	83.6
with Rotary vane pump Penta 35	kg	84.2	84.2	85.6
Power consumption				
with Piston pump XtraDry 150	W	660	660	660
with Rotary vane pump Penta 10	W	665	665	665
with Rotary vane pump Penta 20	W	1100	1100	1100
with Rotary vane pump Penta 35	W	1585	1585	1585

Ultimate pressure in a measuring dome 48 hours after bake-out, can be attained only with metallic seal of the high vacuum flange. (Ultimate pressure with elastomer seal (standard, not bakeable): < 1 · 10⁻⁷ mbar.) 1) without fore-vacuum safety valve

Pfeiffer HiCube 80 Pro **Dimensions**



Dimensions	HiCube 80 Pro	HiCube 80 Pro	HiCube 80 Pro
Flange	DN 40 ISO-KF	DN 63 ISO-K	DN 63 CF-F
A	680 mm	671 mm	676 mm
В	158 mm	149 mm	155 mm

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Pfeiffer HiCube 80 Pro

Features & Benefits

- especially characterized by its extremely fast pump-down times
- features connectivity for digital pressure sensors
- optimal combination of HiPace turbo pump & backing pump
- modular design affords simple customization for application
- service friendly due to accessibility of individual components
- integrated drive electronics
- easy data collection & analysis
- plug & play no installation or cabling required
- · robust engineering makes for long service life
- · optional forevacuum safety valve prevents venting in power failure
- · direct connection of vacuum gauges possible

Applications

- research & development accelerators analysis & surface physics
- vacuum process technology
 general vacuum applications

